



Patent
Attorney's Docket No. 015290-458

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
)
Christopher C. CHANG et al.) Group Art Unit: 1773
)
Application No.: 09/749,917) Examiner: N. Uhlar
)
Filed: December 29, 2000)
)
For: LOW CONTAMINATION PLASMA)
CHAMBER COMPONENTS AND)
METHODS FOR MAKING THE SAME)

AMENDMENT/REPLY TRANSMITTAL LETTER

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Enclosed is a reply for the above-identified patent application.

A Petition for Extension of Time is also enclosed.

A Terminal Disclaimer and a check for [] \$55.00 (248) [] \$110.00 (148) to cover the requisite Government fee are also enclosed.

Also enclosed is _____.

Small entity status is hereby claimed.

Applicant(s) request continued examination under 37 C.F.R. § 1.114 and enclose the [] \$370.00 (279) [] \$740.00 (179) fee due under 37 C.F.R. § 1.17(e).

Applicant(s) previously submitted ___, on ___, for which continued examination is requested.

Applicant(s) request suspension of action by the Office until at least ___, which does not exceed three months from the filing of this RCE, in accordance with 37 C.F.R. § 1.103(c). The required fee under 37 C.F.R. § 1.17(i) is enclosed.

A Request for Entry and Consideration of Submission under 37 C.F.R. § 1.129(a) (146/246) is also enclosed.

No additional claim fee is required.

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An additional claim fee is required, and is calculated as shown below:

AMENDED CLAIMS					
	NO. OF CLAIMS	HIGHEST NO. OF CLAIMS PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	ADDT'L FEE
Total Claims	34	MINUS 31 =	3	× \$18.00 (103) =	\$54.00
Independent Claims	3	MINUS 3 =	0	× \$84.00 (102) =	--
If Amendment adds multiple dependent claims, add \$280.00 (104)					
Total Amendment Fee					
If small entity status is claimed, subtract 50% of Total Amendment Fee					
TOTAL ADDITIONAL FEE DUE FOR THIS AMENDMENT					

A claim fee in the amount of \$ _____ is enclosed.

Charge \$ 54.00 to Deposit Account No. 02-4800.

The Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17, 1.20(d) and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 02-4800. This paper is submitted in duplicate.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

By:



Edward A. Brown
Registration No. 35,033

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P.O. Box 1404
Alexandria, Virginia 22313-1404
(703) 836-6620

Date: April 19, 2002



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In re Patent Application of
Christopher C. CHANG et al.
Application No.: 09/749,917
Filed: December 29, 2000
For: LOW CONTAMINATION PLASMA
CHAMBER COMPONENTS AND
METHODS FOR MAKING THE SAME

Group Art Unit: 1773
Examiner: N. Uhliir

AJ
#4
PA
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AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Official Action dated February 26, 2002, please amend the
above-identified application as follows:

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IN THE SPECIFICATION:

Please replace the paragraph beginning at page 10, line 18, with the following:

An exemplary metal etch reactor of the aforementioned type is a transformer-coupled plasma reactor known as the TCP™ 9600 plasma reactor, which is available from Lam Research Corporation of Fremont, California. FIG. 2 illustrates a simplified schematic of the TCP™ 9600 plasma reactor. In FIG. 2, a reactor 150 including a plasma processing chamber 152 is shown. Above chamber 152, there is disposed an antenna 156 to generate plasma, which is implemented by a planar coil in the example of FIG. 2. The antenna 156 is typically energized by an RF generator 158 via a matching network (not